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PATENT

# IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Ted A. Loxley

Application No.: 09/490, 162 Gro

Filed: 22 January 2000

Group No.: 2812 Examiner: V. Simkovic

For: Process and Apparatus for Cleaning Silicon Wafers

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## AMENDMENT TRANSMITTAL

1. Transmitted herewith is an amendment for this application.

#### **STATUS**

2.	Арр	Applicant is		
	X	a small entity. A statement:		
		☐ is attached.		
		was already filed.		
		other than a small entity.		

## CERTIFICATE OF MAILING/TRANSMISSION (37 C.F.R. § 1.8(a))

I hereby certify that this correspondence is, on the date shown below, being:

#### MAILING

deposited with the United States Postal Service with sufficient postage as first class mail, in an envelope addressed to the Assistant Commissioner for Patents,

Date Seconder 22,2004

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Signature

Vincent A. Greene

(type or print name of person certifying)



### IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Ted A. Loxley :

Serial No. 09/490,162 :

Filed January 22, 2000

For PROCESS AND APPARATUS FOR

CLEANING SILICON WAFERS

Viktor Simkovic - Technology Center 2800 Examiner

Docket No. 104

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

> Amendment After Allowance Under 37 CFR 1.312

Sir:

Please amend the above-identified application by deleting the last paragraph of page 56 and replacing it with the following paragraph:

-- In the practice of the present invention electropurge cleaning with low-voltage wafer charges, such as 2 to 8 volts, can be effective with the dilute RCA and ultra-dilute RCA (SC-1 and SC-2 cleans with or without the assistance of megasonic energy (which can be damaging to delicate nanoscale microcircuits). --